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**PATENT APPLICATION**

UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Attn: OIPE

Noriyoshi SATO et al.

Group Art Unit: 2812

Application No.: 10/539,569

Docket No.: 124305

Filed: August 18, 2005

For: PLASMA GENERATOR, OZONE GENERATOR, SUBSTRATE PROCESSING  
APPARATUS AND METHOD OF MANUFACTURING SEMICONDUCTOR  
DEVICE

**SECOND REQUEST FOR CORRECTION OF PALM RECORDS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

James A. Oliff  
Registration No. 27,075

Tarik M. Nabi  
Registration No. 55,478

JAO:TMN/hjr

Date: July 10, 2006

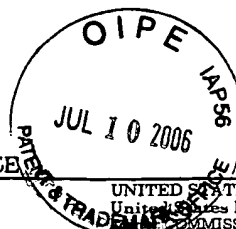
**OLIFF & BERRIDGE, PLC**  
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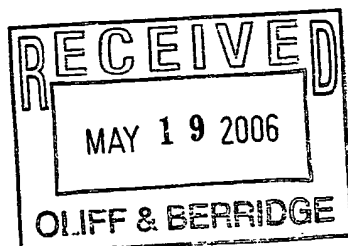


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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/539,569	08/18/2005	2812	2080	124305	18	21	8

25944

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 P.O. BOX 19928  
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CONFIRMATION NO. 4496

FILING RECEIPT



\*OC000000018827530\*

Date Mailed: 05/17/2006

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please mail to the Commissioner for Patents P.O. Box 1450 Alexandria Va 22313-1450. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

## Applicant(s)

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Iwate

Tamiya  
 Assignment for Published Patent Application  
 1) Hitachi Kokusai Electric Inc., Tokyo, JAPAN

Power of Attorney: The patent practitioners associated with Customer Number 25944.

## Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP03/16887 12/26/2003

## Foreign Applications

## Acceptable Request to Retrieve Priority Application Received?

JAPAN ~~2003~~-379963 12/27/2002

NO

2002

If Required, Foreign Filing License Granted: 05/16/2006

The country code and number of your priority application, to be used for filing abroad under the Paris Convention, is US10/539,569

2) Adtec Plasma Technology Co., Ltd., Fukuyama-shi, JAPAN

Projected Publication Date: 08/24/2006

3) Noriyoshi Sato, Miyagi, JAPAN

4) Hiroshi Mase, Ibaraki, JAPAN

Non-Publication Request: No

5) Tamiya Fujiwara, Iwate, JAPAN

**Early Publication Request:** No

**Title**

Plasma generator, ozone generator, substrate processing apparatus and manufacturing method of semiconductor device

**Preliminary Class**

438

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